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Electrodeposited, Transverse Nanowire Electroluminescent Junctions

THESIS

submitted in partial satisfaction of the requirements for the degree of

MASTER OF SCIENCE

in Physics

by

Shaopeng Qiao

Thesis Committee: Professor Reginald M. Penner , Chair Professor Ilya N. Krivorotov Assistant Professor Shane Ardo

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DEDICATION

To my parents and friends.

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- 2.9 EL measurement set-up. The *th-LEJs* was glued on a *Tinch* × *stitches* glass slide then glued on a peltier cooling device using the copper tape. The peltier was used to remove the heat generated during EL measurement. The *tn-LEJs* was connected to a Keithley 2400 sourcemeter, and then the whole device was placed on an inverted microscope stage. The device along with the objective lens were wrapped with regular food wrap to create a sealed environment. The food wrap was then pierced through by a small glass pipe connected with a nitrogen tank. A nitrogen environment was created during EL measurement to avoid water condensation or frost.

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ACKNOWLEDGMENTS

I would like to thank my thesis advisor Professor Reginald M. Penner. With his support, I have learned a lot about electrochemisty, different materials characterization techniques and light emitting devices. He is always very helpful when people come to him and gives out greas advices. He showed great supports for my job hungtings and always looks out opportunities for me. Without him, I would not be able to have all the achievements in my graduate school.

I would like to thank my committee member Professor Ilya N. Krivorotov and Professor Shane Ardo for being on my master thesis committee. Thanks for the patience during the communications and the efforts on my thesis.

I would like to thank my funding agency National Science Foundation, Division of Materials Research through contract DMR-1206867. All the SEM and XRD data were acquired using instrumentation of the LEXI facility (lexi.eng.uci.edu/) at UCI and PL spectra were acquired at the Laser Spectroscopy Facility (LSF) at the Department of Chemistry at UCI. I would like to Dr. Dmitry Fishman, Director of the UCI Chemistry Laser Spectroscopy Facility, for his expert assistance. I would like to thank Professor Rob Corn and his students for providing access to the microscope and CMOS camera used for EL measurements.

I would like to thank all the other members in Penner group especially Dr. Qiang Xu, Dr. Rajen K. Dutta, Dr. Mya Le Thai, Dr Xiaowei Li. for valuable discussions on my research. And also thanks to Alex Fast and Kevin T. Crampton for the help on spectrometer setup.

I would like to thank American Chemical Society for giving me the permission to incorporate my previously published work in ACS Nano into my thesis.

ABSTRACT OF THE THESIS

Electrodeposited, Transverse Nanowire Electroluminescent Junctions

By

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Master of Science in Physics University of California, Irvine, 2018

Professor Reginald M. Penner, Chair

The preparation by electrodeposition of transverse nanowire electroluminescent junctions (tn-ELJs) is described and the electroluminescence (EL) properties of these devices are characterized. The lithographically patterned nanowire electrodeposition process (LPNE) is first used to prepare a long (mm's), linear, nanocrystalline CdSe nanowires on glass. The thickness of these nanowires along the emission axis is 60 nm and the width, w_{CdSe} , along the

electrical axis is adjustable from 100 - 450 nm. Ten pairs of nickel-gold electrical contacts are then positioned along the axis of this nanowire using lithographically directed electrodeposition. The resulting linear array of nickel-CdSe-gold junctions produce electroluminescence (EL) with an external quantum efficiency, EQE, and threshold voltage, V_{th} , that depends sensitively on w_{CdSe} . EQE increases with increasing electric field and also with increasing w_{CdSe} , and V_{th} also increases with w_{CdSe} , and therefore the electrical resistance, of the tn-ELJs. V_{th} down to 1.8(±0.2)V (for $w_{CdSe} \approx 100$ nm) and η_{EL} of 5.5(±0.5) × 10⁻⁵ (for $w_{CdSe} \approx 450$ nm) are obtained. tn-ELJs produce a broad EL emission envelope, spanning

the wavelength range from 600 - 960 nm.

Chapter 1

Introduction

1.1 Electroluminescence from Electrodeposited Semiconductor Nanostructures

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Methods for patterning nanometer-scale electroluminescent (EL) structures on surfaces will be required for a variety of anticipated device applications ranging from chemical sensors, to information transfer and processing, and interfaces to biological systems.[61, 31, 62] Single semiconductor nanostructures were first electrically stimulated to emit light in 2001 when Lieber and coworkers reported light emission at the forward-biased junctions between crossed n-doped and p-doped InP nanowire junctions.[16] Many creative device architectures for nanostructure EL devices have subsequently been demonstrated based upon single nanowires,[3, 68, 69, 14, 18] nanowire arrays interfaced to films,[64, 19, 6] crossed nanowire p-n junctions,[21, 23, 67] and core-shell hetrostructures,[44, 57, 20, 29, 5] In the specific case of devices based upon cadmium selenide (CdSe) - the semiconductor of interest here external quantum efficiencies (EQEs) are generally in the 10^{-7} to 10^{-5} range (Table 1.1).

Work on *films* of thousands or millions of semiconductor nanocrystals preceded experiments on single nanostructures. These films are macroscopic in two dimensions, and nanoscopic in the third, or thickness dimension. Bulovic and coworkers first demonstrated that layers of CdSe nanocrystals could produce EL in 1992.[10] Although EQE for these devices were initially as low as those seen for emissive devices based upon single semiconductor nanostructures,[12, 11] it was soon discovered that the insertion of hole-transporting layers (e.g. PEDOT) and electron-injecting layers (e.g. ZnO) sandwiching the emitting layer elevated the EQE to 1% or higher,[27, 66, 22, 40, 63] (for recent reviews, see: [48, 54]).

By comparison, there has been little work involving EL from *electrodeposited* semiconductor nanostructures.[41, 60, 1] But electrodeposition provides capabilities for device fabrication that are complimentary to those enabled using chemically synthesized nanocrystals or single crystalline nanowires, including the ability to pattern and position emitter structures with high precision.[41] Here, we describe a discovery platform that provides a means for electrodepositing and characterizing the EL properties of linear arrays of many nearly identical metal-semiconductor-metal (M-S-M) junctions. In this work, we use this platform to characterize arrays of nickel-(*nc*-CdSe)-gold M-S-M junctions. These junctions are prepared by first electrodepositing an ensemble of 60 nearly identical *nc*-CdSe nanowires, and then locating nickel and gold contacts on opposite sides of each nanowire along their axes also using electrodeposition. These devices are termed "transverse nanowire electroluminescent junctions" or *tn-ELJs*.

Junction Description ^{a}	Electrode Spacing (nm)	$V_{th}^{\ b}$ (V)	Spectral Range (nm)	$EQE_{max}{}^{c}$	Ref
nanocrystal					
films					
CdSe QD	1000	4	480-650	$1 - 10 \times 10^{-5}$	[11]
CdSe QD-PVK	70-120	5-7	615 - 650	5×10^{-6}	[12]
CdSe QD-TPD	40	3	540 - 590	5.2×10^{-3}	[10]
CdSe-CdS					
core-shell QD		4	600-630	$4-8 \times 10^{-3}$	[66]
CdSe-CdS					
core-shell QD		1.5	600-635	12-18	[30]
CdSe QD TPD		15.5	400-750	1.4×10^{-6}	$\lfloor 46 \rfloor$
• 1					
single					
nanostructures	20	1.7(+0.1)	650 990	10-5	[10]
CdSe NK CdSe NW	9000 6000	$1.7(\pm 0.1)$	620.850	10^{-6}	[10] [14]
Cuse NW	2000-0000	4	020-000	$(1-3) \times 10$	$\lfloor 14 \rfloor$
nc-CdSe					
in a nanogap					
nanocrystals	100-500	1.6 - 1.8	580-720		[15]
$T_{den} = 20^{\circ}C$	200	$1.9(\pm 0.1)$		$1.2(\pm 0.4) \times 10^{-6}$	[60]
$T_{dep} = 75^{\circ}C$	200	$1.5(\pm 0.2)$	650-890	$1.8(\pm 0.7) \times 10^{-6}$	[60]
uep					LJ
$nc ext{-}CdSe$					
NW arrays					
annealed $300^{\circ}C \times 4h$	5000	$16(\pm 5)$		$6(\pm 2) \times 10^{-7}$	[1]
annealed 450°C×1h	5000	$12(\pm 1)$		$8(\pm 2) \times 10^{-7}$	[1]
annealed $300^{\circ}C \times 4h$	600	$6.2(\pm 0.5)$	610-890	$4(\pm 1) \times 10^{-6}$	[1]
CdSe <i>tn-ELJ</i>	102	$1.85(\pm 0.06)$	570-860	$1.3(\pm 0.1) imes 10^{-5}$	This work
	195	$3.8(\pm 0.4)^{'}$	660 - 960 +	$2.4(\pm 0.1) imes 10^{-5}$	"
	313	$5.1(\pm0.3)$	600-960+	$2.5(\pm 0.1) imes 10^{-5}$	22
	398	$6.0(\pm0.5)$	550-960+	$3.6(\pm0.2){ imes}10^{-5}$	"
	448	$6.9(\pm 0.3)$	560-960+	$4.9(\pm 0.2) imes 10^{-5}$	"

Table 1.1: Performance of CdSe Nanostructure-Based Electroluminescent Junctions

^aAbbreviations: NR = nanorod, NW = nanowire, nc = nanocrystals or nanocrystalline, PVK = poly(vinylcarbazole), TPD = N,N' - diphenyl-N,N' - bis(3-methylphenyl) -(1,1'-biphenyl) - 4,4'-diamine ^bV_{th} = E_{app} at the *EL* emission threshold. ^cEQE_{max} = The maximum EQE. 3

1.2 Carrier Generation and Transport in M-S-M Structures

Electroluminescence is generated through the radiative recombination of free electrons and holes either within the material or at the interface between the material and the contact. So the density and distribution of these free electrons and holes would be the key factors for electroluminescence.

For a M-S-M structure, there are three important parts : a) the first metal-semiconductor (M-S) contact; b) the bulk part of the semiconductor material; c) the second M-S contact. These two M-S contacts would form two Schottky barriers on two sides. Upon a potential applied on the two metal contacts, electrons and holes will start to flow within the structure due to the electric force. The band energy diagram for a n-type M-S-M structure is showed in Figure 1.1. [56, 55, 9] (We are only interested in n-type semiconductor here since the material CdSe we study is a n-type semiconductor.)

For these two M-S contacts, free electrons are injected from the right contact which forms a reverse biased Schottky barrier with the middle semiconductor and holes are injected from left contact which forms a forward biased Schottky barrier with the middle semiconductor. As Firgure 1.1 shows, there are two barriers for electron flow at these two contacts: ϕ_{Bn} and ϕ_{in} . ϕ_{in} is much smaller than ϕ_{Bn} and would become 0 when E_{app} is big enough. So the limiting factor for electron flow is ϕ_{Bn} at the right Schottky barrier. For a n-type semiconductor, the carrier concentration of holes is much lower than the carrier concentration of electrons, so the contribution of holes to the current can be ignored. However, hole injection still plays an very important role here. When holes are injected from the left contact into the middle semiconductor, hole concentration of free electrons and holes within a n-type semiconductor where hole concentration is very small compared to electron concentration. In



Figure 1.1: Band energy diagram for a M-S-M structure under an applied potential. E_{app} is the applied potential, Φ_{Bn} is the Schottky barrier height for electrons, Φ_{Bp} is the Schottky barrier height for holes, Φ_{in} is barrier height caused by the build in potential for electrons which is equal to $V_{bi} - V_1$ where V_{bi} is the build in potential and V_1 is the potential distributed on this M-S interface

summary, the limiting factor for total current or carrier injection at the two M-S contacts is the barrier height at the reverse biased Schottky barrier.

For the bulk part, free electrons could be generated from traps. Since the energy level of traps is lower than the conduction band, extra energy would need to be provided for electrons to jump from this barrier. Similar as Schottky emission, this process can be realized through thermal activation. Under electric field, the barrier height could be lowered and this thermal activation process could be enhanced. This is called Poole-Frenkel emission. [49, 9] Besides electron emission, electron transport also happens within the bulk part and there could be several different situations.

Hopping Conduction. With outside potential or electric field, electrons could hop from one trap site to another trap site due to the tunneling effect. It depends on the trap depth or the distance between the trap state and the bottom of conduction band, the distance between two traps, and also the field strength.

Space Charge Limited Conduction. When free electrons are injected into intrinsic and low doped semiconductor, the electron flow could be affected a lot by space charges which make the electric field ununiform in the material. Space charge limited conduction (SCLC) is characterized by Child's law[7] or Mott-Gurney's law[33] which features $I \propto V^2$. For a M-S-M structure with SCLC, I - V curve usually has three regions: 1) Ohmic like conduction region where I - V curve is linear or $I \propto V$; 2) Child's law region which has $I \propto V^2$; 3) traps-filled-limit (TFL) region which has a enormously steep current rise. With lnI - lnVcurve, the slope would correspond to 1, 2, > 2 regions. [17, 26, 45, 35, 9]

Grain-Boundary-Limited Conduction. For a polycrystalline material, there are a lot of grain boundaries. When electrons flow to a grain boundary, it would experience a much higher resistivity than that in the grain. In terms of energy, the grain boundary function like an energy barrier and it would limit the electron flow. [43, 53] Under extra electric field, the barrier height could also be lowered like Poole Frenkel emission. So experimentally this process might not be able to be indentified out separately.

In summary, carrier injection and transportation in a n-type M-S-M structure is dominated by the electron injection and transportantion. This process could be limited by the contact or the bulk depending on the material properties and the device geometry. Through the shape of I - V curve, we might be able to tell which part is the limiting factor.

Chapter 2

Electrodeposited, Transverse Nanowire Electroluminescent Junctions

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2.1 Process Flow

tn-ELJs are prepared using a process (Figure 2.1) that provides for precise control of the width (\pm 5 nm) of the CdSe nanowire - which coincides with the electrical axis of the device - and the height (\pm 2 nm) the CdSe nanowire - which corresponds to the optical axis of the device. A second attribute of tn-ELJs is that the two metal-semiconductor junctions are both prepared by electrodeposition, thereby insuring electrically intimate contact between



Figure 2.1: Simplified process flow for the fabrication of a single transverse nanowire electroluminescent junction (tn-ELJ). In Step 1, an evaporated nickel film on glass is patterned using photolithography. After spincoat of a photoresist (PR) layer and some additional processing, a horizontal trench is produced adjacent to the edge of the nickel film. This trench has dimensions of 60 nm (height), 20 μ m (length) and 300 nm $\sim 1\mu$ m (depth). In Step 2, this patterned nickel edge is immersed in a plating solution and CdSe nanowires are electrodeposited within the trench using the nickel edges as working electrodes. The width of the CdSe nanowires is controlled by the electrodeposited onto each CdSe nanowire. A gold electrical contact is then electrodeposited onto each CdSe nanowire. After the trench is filled with gold, the excess gold emerges from the trench forming a bump, as depicted in Step 3. In Step 4, a gold film is evaporated onto the entire surface of the device and then, in Step 5, the gold-coated photoresist layer is removed by lift-off. tn-ELJ devices produce EL light emission upon the application of a voltage bias to the nickel and gold contacts.

nickel and CdSe (Figure 2.1, step 2), and subsequently, CdSe and gold (Figure 2.1, step 3). Finally, in contrast to stacks of 2D films where the electrical and optical axes are coincident, the optical axis of the *tn-ELJ* is orthogonal to the electrical axis, allowing independent optimization of these dimensions for these two functions. The precision of *tn-ELJ* fabrication exposes the dominant influence of the *nc*-CdSe nanowire width, w_{CdSe} , on the two major metrics characterizing *EL* performance - the threshold for light emission, V_{th} , and the *EQE*.



Figure 2.2: tn-ELJ device pictures. a) Photograph of 6 individual Ni-CdSe-Au tn-ELJ array devices on glass. The CdSe nanowires are vertically oriented along the left edge of the gold film. b) Photomicrograph of one of the six devices. Each device has ten individual nickel contacts to CdSe nanowires, and each is 20 μ m in width.

2.2 Results and Discussion

2.2.1 Electrodeposition

tn-ELJs were prepared using a version of the lithographically patterned nanowire electrodeposition (LPNE) process (Figure 2.1) that we have previously described.[59, 32] The lithographically patterned nickel electrode that is employed for CdSe electrodeposition serves as one electrical contact to a CdSe nanowire, and the second gold electrode is electroplated at the CdSe surface (Figure 2.1). This process, carried out in parallel, provides a means for preparing a total of sixty pairs of nickel-gold electrodes in groups of ten, coupled with sixty nearly identical CdSe nanowires (Figure 2.2).

Uniformity of the CdSe nanowire width is achieved by electrodepositing the CdSe nanowire according to the reaction: $Cd^{2+} + H_2SeO_3 + 4H^+ + 6e^- \rightarrow CdSe(s) + 3H_2O$ under conditions of activation control. Here, this was accomplished using potentiostatic deposition at -0.60 V vs. SCE (Figure 2.3a). Electrodeposition current *versus* time transients (Figure 2.3b) show increasing current indicative of an increase in the wetted surface area of the nascent nanowire during electrodeposition. This increase in wetted surface area is likely the result of



Figure 2.3: Electrodeposition of CdSe nanowires (a,b) and a gold contact (c,d). a) Cyclic voltammetry (50 mV/s) in the plating solution used for CdSe electrodeposition, containing 0.30 M $CdSO_4$, 0.70 mM SeO_2 , and 0.25 M H_2SO_4 at pH 1-2. b) Current versus time transient for the potentiostatic growth at -0.60V of CdSe nanowires. CdSe nanowires with widths, w_{CdSe} , ranging from 102 nm to 448 nm were prepared by increasing the electrode-position time from 20s to 100s. c) Cyclic voltammogram (50 mV/s) for a commercial gold plating solution acquired using the edges of CdSe nanowires. d) Current versus time transient for the potentiostatic growth at -0.90V of gold contacts at the CdSe nanowires. A rapid increase in current, starting at 650s, signals the filling of the photoresist trench.

the deposition of a porous CdSe deposit, since voids are visible in some of the SEM images presented below (Figure 2.4).

In each tn-ELJ, the lithographically patterned nickel electrode used to grow the CdSe nanowires serves as one electrical contact. The second contact, composed of gold, is prepared by electrodeposition directly onto the edge of the freshly-deposited CdSe nanowire. Again, this process is accomplished by the slow, activation-controlled deposition of gold (potentio-static deposition at -0.90 V vs. SCE (Figure 2.3c)). A quasi-constant deposition current is observed during this process (Figure 2.3d) until the trench fills with gold (Figure 2.3d, 650s). At longer times, a rapid increase in the gold deposition current is observed resulting in the formation of a linear gold bump at the mouth of the trench, parallel to the CdSe nanowire (Figure 2.4a.) tn-ELJ device fabrication is completed by vapor depositing additional gold to facilitate the attachment of electrical leads.

2.2.2 SEM Characterization

SEM images of tn-ELJ Ni-CdSe-Au junctions (Figure 2.4) show that the width of the CdSe nanowire is conformal with respect to the nickel electrode (Figure 2.4a and inset) and directly proportional to the electrodeposition time. EDX elemental analysis (Figure 2.4c,e) shows the CdSe layer to be stoichiometric (Cd:Se=1.02±0.01) within the precision of this measurement. Five tn-ELJ with different w_{CdSe} values, shown in Figure 2.4f-j, were investigated in this study. In recent prior work, [2, 60, 1, 25, 24] the properties of the nc-CdSe produced by an identical procedure have also been characterized by x-ray diffraction, Raman spectroscopy, and transmission electron microscopy. Electrodeposited nc-CdSe is crystalline, possesses a cubic crystal structure, and has a mean grain diameter of ≈ 5 nm. [2, 60, 1, 25, 24]



Figure 2.4: Scanning electron micrographs of tn-ELJ Ni-CdSe-Au junctions, all 60 nm in thickness. a) Low magnification image showing the horizontal CdSe nanowire, with top gold and bottom nickel electrodes. INSET: Higher magnification SEM image of the indicated region. b-e) EDX elemental maps of the junction region shown in the inset of (a) showing regions of Au (b), Cd (c), Ni (d), and Se (e). f-j) SEM images of five Ni-CdSe-Au tn-ELJ having w_{CdSe} varying from 102 nm (f) to 448 nm (j).



Figure 2.5: Electrical characterization of Ni-CdSe-Au *tn-ELJs.* a,b) Current versus voltage plots showing: a) low voltage ($E_{app} < 1.0$ V) and, b) high voltage region ($E_{app} > 1$ V in positive polarity only. c) Plot of Ln(I) versus Ln(E_{app}) showing the slopes of linear regions of the I - V data. The dashed red line and dashed black lines are the predictions of Eq. 1 for back-to-back Schottky barriers, using the parameters of Table 2.1 for $w_{CdSe} = 102$ nm and 448 nm, respectively. d) Plot of Ln(I/ \mathcal{E}) versus $\mathcal{E}^{1/2}$ highlighting linear regions, consistent with possible Poole-Frenkel emission at high \mathcal{E} . e) Plot of Poole-Frenkel field lowering coefficient, β_{pf} , as a function of w_{CdSe} for both high \mathcal{E} (>3 × 10⁷ V/m) and low \mathcal{E} regions.

w_{CdSe} (nm)	$\begin{array}{c} A^{**a} \\ (A \ cm^{-2} \ K^{-1}) \end{array}$	$\phi_{B1}{}^b$ (eV)	$\phi_{B2}{}^c$ (eV)	$n_1{}^d$	n_2^e
102 195 313 399 448	$15.6 \\ 15.6 \\ 15.6 \\ 15.6 \\ 15.6 \\ 15.6$	$\begin{array}{c} 0.52 \\ 0.52 \\ 0.55 \\ 0.58 \\ 0.62 \end{array}$	$\begin{array}{c} 0.57 \\ 0.55 \\ 0.56 \\ 0.59 \\ 0.64 \end{array}$	$\begin{array}{c} 1.295 \\ 1.185 \\ 1.125 \\ 1.147 \\ 1.239 \end{array}$	$ 1.196 \\ 1.127 \\ 1.130 \\ 1.086 \\ 1.209 $

Table 2.1: Fitting Parameters For Calculations of I-V Curves According to the Back-to-Back Schottky Barrier Model (Eq. 1)

 ${}^{a}A^{**} = \text{effective Richardson constant.}[42]$

 ${}^{b}\phi_{B1}$ = Schottky barrier height for Ni-CdSe contact.

 ${}^{c}\phi_{B2}$ = Schottky barrier height for Au-CdSe contact.

 $^{d}n_{1} =$ ideality factor for Ni-CdSe contact

 ${}^{e}n_{2} = \text{ideality factor for Au-CdSe contact}$

2.2.3 Current Transport

Transport in metal-semiconductor-metal (M-S-M) junctions where both junctions are Schottky barriers was studied by Sze *et al.* in 1971[56] and subsequently by others.[39, 37, 8] With the application of a potential, E_{app} , the M-S-M has one forward biased Schottky barrier (with (+) polarity) and one reverse biased Schottky barrier ((-) polarity) and transport, predominantly by majority electrons, is controlled by the reverse-biased junction. Current *versus* E_{app} (or *I-V*) curves are characterized by exponentially increasing current and, for identical metal contacts, are symmetrical about $E_{app} = 0$, conforming to the equation:[52, 8, 51]

$$J(V) = \frac{J_1 J_2 sinh(\frac{qV}{2KT})}{J_1 exp(\frac{qV}{2n_1KT}) + J_2 exp(-\frac{qV}{2n_2KT})}$$
(2.1)

Where J_1 , for example, is given by:[55]

$$J_1 = A^{**}T^2 exp(-\frac{\phi_{B1}}{KT})$$
(2.2)

and the equation for J_2 is analogous. Here A^{**} is the effective Richardson constant. For CdSe, $A^{**} = 15.6 \text{ A cm}^{-2} \text{ K}^{-1}$).[42] ϕ_{B1} and ϕ_{B2} are the Schottky barrier heights of the Au-CdSe and Ni-CdSe contacts, respectively, and n_1 and n_2 are the two ideality factors for these junctions. Eq. 2.1 does an excellent job of fitting our experimental *I-V* curves for all five tn-*ELJs* and w_{CdSe} values (Figure 5a). The fitting parameters required to produce these curves (Table 2.1) are also physically reasonable, involving the known Richardson constant and barrier heights in the range from 0.52 - 0.64 eV - close to those reported for macroscopic CdSe-Au Schottky barriers.[58] We conclude that for $|E_{app}| < 1.0 \text{ V}$, *I-V* curves for tn-*ELJs* are well described by the back-to-back Schottky barrier model.[39, 37, 8]

For $|E_{app}| > 1.0$ V, however, the currents predicted by Eq. 2.1 are significantly higher than those observed experimentally for *tn-ELJs*. For example, using the parameters of Table 2.1, dashed lines in Figure 2.5c show the predicted *I-V* behavior for the 102 nm (red dashed line) and the 448 nm (black dashed line) *tn-ELJs*. A comparison of the dashed curves with the experimental data points of the same color shows that the disparity between them increases with increasing E_{app} . This disparity is explained by the presence of a highly resistive CdSe layer in the *tn-ELJs*, sandwiched between the two Schottky barriers. Based upon the analysis of these currents described below, we conclude that transport through a *tn-ELJ* is not limited by transport at one or both of the Schottky barriers, but by processes occurring in the bulk of the CdSe, even though this "bulk" is nanoscopic in both length (\approx 100-450 nm) and thickness (60 nm). Information on the transport mechanisms operating within the CdSe can be obtained by analyzing the E_{app} dependance of the current. Space charge limited conduction (SCLC) has previously been proposed to model the *I-V* behavior of Au-CdSe-Au junctions.[38] SCLC conforms to the Mott-Gurney Eq.:[33]

$$J = \frac{9\epsilon_s \mu (E_{app})^2}{8d^3}$$
(2.3)

where J is the current density (A/m²), μ is the carrier mobility (m²/(V·s)), $\epsilon_s = -7.82 \text{ x}$ 10⁻¹¹ F/m for CdSe, and $d = w_{CdSe}[33]$ Eq. 2.3 predicts that Ln(I) versus Ln(E_{app}) will have a slope of 2.0, and this behavior is observed for four of the five of the CdSe thicknesses (Figure 2.5c); $w_{CdSe} = 399 \text{ nm}$ instead shows a slope of 2.6. In this potential regime, SCLC is likely the dominant mechanism of charge transport. At lower E_{app} , a slope of 1.0, indicative of ohmic conduction, is seen for several w_{CdSe} ($w_{CdSe} = 195$ and 313 nm). Slopes larger than 2.0 are observed for all devices at $E_{app} > 10$ V. As previously described,[35, 4, 47] slopes exceeding 2.0 signal that the SCLC current is augmented by other transport mechanisms such as P-F emission or Schottky emission.

P-F emission conforms to Eq. 2.4 while, as already indicated, Schottky emission is modeled by Eq. 2.1:[49, 50, 55]

$$J = J_0 \exp\left(\frac{\beta_{pf} \mathcal{E}^{1/2}}{kT}\right) \tag{2.4}$$

where β_{pf} is the P-F field-lowering coefficient and \mathcal{E} is the magnitude of the electric field $(E_{app}/d).[50, 55]$ These two mechanisms both predict linear $Ln(I/\mathcal{E})$ versus $\mathcal{E}^{1/2}$, which we

w_{CdSe} (nm)	Slope 1	Slope 2	Slope 3	Slope 4
102 195 313 399 448	$\begin{array}{c} - \\ 1.1 \ (\pm 0.1) \\ 1.03 \ (\pm 0.06) \\ - \\ - \\ - \end{array}$	$\begin{array}{c} 2.03 \ (\pm 0.05) \\ 2.00 (\pm 0.05) \\ 1.9 \ (\pm 0.1) \\ 2.63 \ (\pm 0.05) \\ 2.0 \ (\pm 0.2) \end{array}$	$5.2 (\pm 0.2) 5.7 (\pm 0.1) 3.77 (\pm 0.07) 5.5 (\pm 0.1) 4.33 (\pm 0.07)$	$ \begin{array}{c} 10 (\pm 1) \\ - \\ 4.8 (\pm 0.2) \\ - \\ - \\ - \\ \end{array} $

Table 2.2: Discrete Slopes of $\operatorname{Ln}(I)$ versus $\operatorname{Ln}(E_{app})$ Plots Observed at Progressively Higher E_{app}

observe at high values of $\mathcal{E} > 3 \times 10^7$ V/m for all five devices (Figure 2.5d).

From the slope of these plots, an experimental value of β_{PF} can be calculated and compared with the theoretically expected value for CdSe of 2.55 × 10⁻⁵ $eVm^{-1/2} V^{1/2}$, indicated by the horizontal blue dashed line in Figure 2.5d. In the high \mathcal{E} region > 3 × 10⁷ V/m, we measure β_{pf} values in the range from 1.5 - 2.9 × 10⁻⁵ eV m^{1/2} V^{-1/2} - close to that expected for Poole-Frenkel emission in CdSe (Figure 2.5e). The best agreement is seen for the thinnest tn-ELJs ($w_{CdSe} = 102$ and 195 nm) where β_{pf} values are in the range from 2.6-2.9 × 10⁻⁵ eV m^{1/2} V^{-1/2}. Much larger values of β_{pf} are seen in the low \mathcal{E} region < 2 × 10⁷ V/m where we believe that SCLC, not Poole-Frenkel or Schottky emission, is the dominant mechanism of charge transport. We interpret a high level of agreement of the experimental β_{pf} value with the theoretical value to suggest the likely prevalence of P-F emission, as opposed to Schottky emission, in tn-ELJs at high \mathcal{E} .

To summarize these observations, our analysis of tn-ELJs reveals the operation of up to three discrete charge transport mechanisms in parallel - ohmic conduction, SCLC, and (likely) P-F emission - with increasing importance of SCLC and P-F emission as E_{app} increases. The values of these discrete slopes (see in the plot of Figure 2.5c), which delineate voltage intervals in which particular mechanisms are operating, are tabulated in Table 2.2.



Figure 2.6: Optical micrograph of EL emission as a function of E_{app} for a ten-element tn-ELJs with $w_{CdSe} = 102$ nm. At left is shown an optical micrograph of the ten electrode array, showing the vertical orientation of the CdSe nanowire and the position of the nickel contacts.

2.2.4 Electroluminescence Intensity and External Quantum Efficiency

EL emission from ten-element arrays of Ni-CdSe-Au tn-ELJs (Figure 2.6) was imaged as a function of E_{app} using an inverted optical microscope (Figure 2.9). For the $w_{CdSe} = 102$ nm device, all ten channels produce EL at $E_{app} = 3$ -4V, but EL emission intensity increases with E_{app} and is non-uniformly distributed within each channel and between different channels (Figure 2.6) - a characteristic feature of EL in these systems that we discuss below. The properties this EL emission depended sensitively on the width of the CdSe emitter layer, w_{CdSe} (for a constant 60 nm height of this emitter layer, Figure 2.7a). For example, the voltage threshold for EL emission, V_{th} , increases from 2V to 7V in direct proportion to w_{CdSe} (Figure 2.7a,b). This trend is also evident in prior work involving CdSe EL emitting device structures where the spacing of electrodes has been varied (Table 1.1), and it derives in part from the ohmic resistance imposed by the emitter layer. The lowest values for V_{th} are



Figure 2.7: Optical characterization of Ni-CdSe-Au *tn-ELJs.* a) *EL* intensity *versus* E_{app} for five widths of devices described in Figure 2.5. Error bars represent $\pm 1\sigma$ for *n* devices as follows: n = 3 ($w_{CdSe} = 102 \text{ nm}$), n = 3 (195 nm), n = 4 (313 nm), n = 4 (399 nm), and n = 3 (448 nm). b) Threshold voltage, V_{th} , *versus* w_{CdSe} . Here, V_{th} is estimated as the lowest voltage at which *EL* emission is observed above background. c) External quantum efficiency (EQE) versus electric field, \mathcal{E} for the five devices described in Figure 2.5. d) *EQE versus* average device current. e) *EQE* for the five devices described in Figure 2.5, each corresponding to five discrete \mathcal{E} values: 2.85, 3.90, 4.15, 5.15, 5.50 (× 10⁷ V/m).

those where the narrowest electrode spacings were used. For example, Gudiksen *et al.*[18] reported a V_{th} of 1.7V for *EL* emission from transistors with electrode spacings of 30 nm. *EL* from gold nanogaps that are 100-200 nm in width and filled with electrodeposited CdSe[60] are characterized by $V_{th} = 1.5 - 1.9$ V. It should be noted that even lower values of V_{th} have been demonstrated in cases where hole and electron transporting layers have been added on either side of the CdSe emitted layer, irrespective of the electrode spacing.[30, 27, 54, 65, 46]

the maximum EL intensity produced at $w_{CdSe} = 102$ nm using 3V is twice as high as the maximum EL intensity measured for the 448 nm tn-ELJs at 26V (Figure 2.7a). But the quantum efficiency of EL emission is actually inversely correlated with w_{CdSe} . In the plot of external quantum yield (EQE) versus the electric field, \mathcal{E} (Figure 2.7c), devices with all five values of w_{CdSe} show similar EQE values at low \mathcal{E} of $\approx 2 \times 10^7$ V/m. But for higher fields of up to 6×10^7 V/m, EQE is preferentially increased for the widest emitter layers ($w_{CdSe} = 313$, 399, and 448 nm). At high fields, for example, the 448 nm tn-ELJs produces an EQE ($\approx 5 \times 10^{-5}$) that is five times as high as the maximum EQE measured for the 102 nm tn-ELJs. This EQE is amongst the largest measured for CdSe EL devices that do not have dedicated hole and/or electron injection layers (Table 1.1).

A plot of EQE versus current (Figure 2.7d) shows that, in general, EQE increases monotonically with increasing current. The slope of this increase is correlated with w_{CdSe} . The exception to this rule involves the narrowest emitter layer, $w_{CdSe} = 102$ nm, where the EQEfirst increases, and then reaches a plateau at a maximum EQE of $\approx 1.2 \times 10^{-5}$. Wider CdSe layers show more steeply sloping EQE versus current behavior, and larger EQE_{max} as current is increased, but the maximum attainable current and therefore EQE in wide CdSe emitter layers are both limited (Figure 2.7d).

In Figure 2.7e, the EQE is plotted for tn-ELJs as a function of w_{CdSe} for five discrete \mathcal{E} values. This plot highlights the fact that wide CdSe emitter layers produce elevated EQE

only at high fields, $\mathcal{E} > 5 \times 10^7 \text{ V/m}$. At lower \mathcal{E} values, EQE for tn-ELJs with five w_{CdSe} are within a factor of two of each other (Figure 2.7e).

2.2.5 Electroluminescence Spectra and Mechanisms

A typical *EL* spectrum for a *tn-ELJs* (Figure 2.8a) shows a broad emission envelope spanning the wavelength range from 500 nm to 1000 nm. A photoluminescence (PL, $\lambda_{ex} = 532$ nm) spectrum for electrodeposited *nc*-CdSe is much narrower, and centered at the 725 nm bandgap, E_{bg} , of CdSe (Figure 2.8). This dramatic broadening of the spectral output in EL as compared with PL has been observed in many previous studies involving a range of materials. [3, 15, 28, 14, 18, 46] A second characteristic feature of EL emission in tn-ELJs, already seen in Figure 2.6, is that the EL produced within a 20 μ m wide element consists of a series of sub-micron point emitters - even at high E_{app} . This is apparent in the images and plots of Figure 2.8b that show emission from a $w_{CdSe} = 195$ nm tn-ELJ at E_{app} from 4.5 V to 13.5 V. One possible reason for localized light emission is modulation of the electric field along the axis of each CdSe nanowire, caused by its width nonuniformity. In this case, local constrictions in width would correlate with a locally higher \mathcal{E} and enhanced EL emission. The number and total area of the light emitting regions increases with E_{app} . The spectrum of Figure 2.8a was acquired for a device consisting of ten tn-ELJs, and therefore contains many point emitters. Spectra for single point emitters could not be acquired in this study, but there is evidence that the broad emission seen in Figure 2.8a is produced by each point emitter and is not the sum of many narrower emission spectrs produced by an ensemble of point emitters. The evidence takes the form of the potential dependence (Figure 2.8a). At low E_{app} values (≈ 4 V), just a handful of point emitters are observed and the total ELintensity is very low, but the spectral width of the EL emission is similar to that seen at higher E_{app} values, although emission is somewhat red-shifted. This observation suggests that each micron-scale emitter produces a broad spectrum and that the spectral width seen



Figure 2.8: Spectra and proposed mechanism for EL emission. a) EL spectra as a function of E_{app} for a ten-element tn-ELJs with $w_{CdSe} = 102$ nm. PL spectrum acquired with excitation at $\lambda_{ex} = 532$ nm. b) Micrographs and intensity plots for a $w_{CdSe} = 195$ nm tn-ELJs at four $E_{app} = 4.5$ V - 13.5V. EL emission consists of a series of sub-micron point emitters that coalesce at high E_{app} . c) Schematic energy level diagram for a wide ($w_{CdSe} = 400$ nm) nc-CdSe emitter layer illustrating the presence of deep trap states for electrons and holes, and the presence of a dead layer in which e^-/h^+ recombination is nonradiative. d) Same diagram as in (c) except illustrating a narrow ($w_{CdSe} = 150$ nm) nc-CdSe emitter layer, e) Processes contributing to broad-band EL emission including hot electron-hole recombination ($h\nu > E_{bg}$, green), band-edge emission ($h\nu \approx E_{bg}$, orange), and free hole-trapped electron recombination ($h\nu < E_{bg}$, red).

for many emitters (e.g., Figure 2.8a) is not a function of the number of emitters, with each producing a much narrower emission envelope.

A schematic band diagram (Figure 2.8c-e) illustrates the salient features of EL emission in these nickel-(*nc*-CdSe)-gold *tn-ELJs*. The observed reduction in EQE with decreasing w_{CdSe} (Figure 2.7d,e) suggests the presence of "dead layers" adjacent to the metal contacts within which EL is quenched. This phenomenon has been described previously in connection with EL in thin-film M-S-M devices,[13, 34] but the mechanism responsible for dead layers remains unresolved. One possible mechanism accounting for a dead layer adjacent to metal contacts is the physical diffusion/migration of electrons and/or holes to these metal contacts and their subsequent radiationless recombination. In this case, the thickness of the dead layers should approximate the minority carrier diffusion length, estimated to be 30-50 nm based upon our prior measurements of carrier mobilities [2] and minority carrier lifetimes[25] in electrodeposited *nc*-CdSe. A second possibility, also suggested by others,[36] is that radiationless recombination near a contact is a symptom of poorer CdSe quality, in terms of impurities and crystallinity. Further work will be required to elucidate this mechanism.

Also as depicted in Figure 2.8c-e, the *nc*-CdSe emitter contains deep traps for both electrons and holes, associated mainly with disorder and inpurities at grain boundaries. As E_{app} is increased, \mathcal{E} exceeds the threshold for P-F emission (> 5 × 10⁷ V/m) which triggers the release by field-ionization of trapped holes. Field-emitted, mobile holes rapidly and radiatively recombine with electrons to produce EL. The broad spectral envelope for ELemission seen in Figure 2.8a is accounted for by the operation of three processes in parallel (Figure 2.8e): i) hot electron-hole recombination ($h\nu > E_{bg}$, green), ii) band-edge emission ($h\nu \approx E_{bg}$, orange), and, iii) free hole-trapped electron recombination ($h\nu < E_{bg}$, red). But although EL emission that is red-shifted from E_{bg} is likely caused by trapped carriers, it remains unclear (also in other studies) why the electron and hole traps leading to red-shifted emission in EL are preferentially populated in EL relative to PL.

2.2.6 Conclusion

In conclusion, we describe a discovery platform that consists of arrays of transverse nanowire light emitting nanojunctions or tn-ELJs. These device arrays have the potential to advance our understanding of EL in electrodeposited materials - in this case, arrays of nickel-(nc-CdSe)-gold tn-ELJs. These tn-ELJs exhibit highly reproducible, and tunable, properties for EL light emission that are strongly influenced by the width of the CdSe emitter layer along the electrical axis, w_{CdSe} . Transport in *tn-ELJs* involves a progression of three mechanisms as E_{app} is increased - ohmic conduction, space-charge limited conduction, and Poole-Frenkel (P-F) emission. The voltage threshold for light emission, ranging from 2 V to 7 V, is directly proportional to w_{CdSe} from 100 nm to 450 nm. The external quantum efficiency (EQE) of the observed EL increases for all tn-ELJs with the applied electric field, suggesting that P-F emission of mobile holes into the valance band is rate-limiting. Finally, the maximum external quantum efficiency (EQE_{max}) also increases monotonically with w_{CdSe} , up to 5 × 10^{-5} for $w_{CdSe} = 450$ nm. These observations are consistent with a mechanism of EL light emission involving the P-F emission of holes in the valence band of the electrodeposited *nc*-CdSe nanowire, with subsequent radiative recombination with electrons that are both injected above the conduction band-edge (hot electrons), and others that are trapped, leading to a broad spectral bandwidth for the emission process. Working in opposition to this process is nonradiative electron-hole recombination near (within 30-50 nm) the metal electrical contacts, leading to higher EQE in wide CdSe emitters.

The maximum EQE obtained here of 5×10^{-5} is low, but comparable or better than in previous studies where the same M-S-M architecture has been studied (Table 1.1). In future work, the influence of dedicated hole and electron injecting and transporting layers adjacent to the CdSe emitter layer will be evaluated as a means for obtaining higher *EL* quantum efficiencies.[48, 54]

2.3 Methods

2.3.1 Device Fabrication

CdSe light emitting devices were fabricated using the LPNE method in combination with several additional photolithography steps (Figure 2.1). First, a 60 nm thick layer of nickel was thermally evaporated on a precleaned soda lime glass slide (2.5 cm × 2.5 cm × 1 mm). Then a layer of photoresist (PR, Shipley, S1808) was spin-coated (2500 rpm, 80 s) onto the nickel surface, followed by a soft-bake at (90°C) for 30 min. The PR-coated nickel was then covered with a contact mask, exposed to UV light, and the exposed PR was developed for 20 s (Microposit, MF-319), rinsed with water (Millipore MilliQ, $\rho > 18 \text{ M}\Omega \cdot \text{ cm}$), and air dried. The freshly exposed nickel layer was then removed using nickel etchant (Alfa Aesar) for 2 min, resulting in six parallel 10-finger patterns consisting of 20 μ m wide Ni-CdSe-Au *tn-ELJs* spaced by 5 μ m (Figure 2.2). The photoresist layer was then removed with acetone and a second layer of photoresist (Shipley, S1808) was spin-coated and photolithographically patterned. Exposed nickel was over-etched in 0.80 M nitric acid for 6 8 min to create a horizontal trench with a width of 300 nm ~ 1 μ m at the end of each nickel finger.

CdSe nanowires were electrodeposited into these trenches potentiostatically at -0.60 V versus saturated calomel electrode (SCE) in an unstirred, room temperature, aqueous plating solution consisting of $0.30M CdSO_4$, $0.70mM SeO_2$, and $0.25 M H_2SO_4$ at pH 1-2. (Caution: both $CdSO_4$ and SeO_2 are highly toxic). Gold contacts were then electrodeposited onto the solution-exposed edge of the CdSe nanowire potentiostatically at -0.90 V versus SCE using a Clean Earth Inc. gold plating solution. Gold deposition was continued until the gold emerged from the trench, as signaled by an increase in the electrodeposition current (Figure 2.3d). All electrodeposition operations were carried out using a Gamry Series G 300 potentiostat in conjunction with a one compartment three-electrode electrochemical cell with SCE as the reference electrode and platinum foil as the counter electrode. After gold electrodeposition, a layer of gold was thermally evaporated to form a connection with the electrodeposited gold contact, facilitating the attachment of wire contacts. The PVD-deposited gold on the photoresist coated portion of the device was removed by lift-off.

2.3.2 Structural Characterization

Scanning electron microscopy (SEM) images were acquired using a FEI Magellan 400 XHR system at an accelerating voltage of 1 or 8 keV without metal or carbon coating. Energy-dispersive X-ray spectroscopy (EDS) images were also acquired using this instrument which is equipped with a 80 mm^2 silicon drift X-ray detector (Oxford Instruments, with Aztec software).

2.3.3 Electroluminescence and Photoluminescence

EL images as a function of bias were acquired using an inverted microscope (Olympus, IX71) equipped with a $40 \times$ objective lens (Olympus, LUCPlanFLN 40×0.60) and a CMOS camera (Andor, Neo) as Figure 2.9 shows. Electrical measurements during *EL* emission were accomplished using a sourcemeter (Keithley 2400) controlled by LabVIEW software. EQE was calculated using the number of photons out of *tn-ELJs* devices devided by the number of electrons flowing through the material per second. Cmos sensitivity and geomtry loss was factored into calculation. *EL* spectra were obtained using a spectrometer (Andor, Shamrock SR-500i-D2) equiped with a 300 l/mm grating blazed at 760nm and a CCD camera (Andor, Newton). All the *EL* measurements were carried out under cooling condition using a Peltier cooling device (Custom Thermoelectric, 19012-5L31-06CQQ-X) in nitrogen environment(to avoid water condensation or frost). PL spectra were acquired using a SpectraPro 2300i spectrometer (Princeton Instruments, Acton) excited by a 532nm laser.



Figure 2.9: EL measurement set-up. The tn-LEJs was glued on a $1inch \times 3inches$ glass slide then glued on a peltier cooling device using the copper tape. The peltier was used to remove the heat generated during EL measurement. The tn-LEJs was connected to a Keithley 2400 sourcemeter, and then the whole device was placed on an inverted microscope stage. The device along with the objective lens were wrapped with regular food wrap to create a sealed environment. The food wrap was then pierced through by a small glass pipe connected with a nitrogen tank. A nitrogen environment was created during EL measurement to avoid water condensation or frost.

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